Amendments to the Claims:

This listing of claims will replace all prior versions, and listings of claims in the application:

Listing of Claims:

1-17. (canceled)

- 1 18. (previously presented) A method as in claim 24 wherein step (b) advances 2 curing of the thermosetting resin.
 - 19. (canceled)
- 20. (previously presented) A method as in claim 24 further comprising a step of inspecting the semiconductor device.
- 21. (previously presented) A method as in claim 24 wherein the semiconductor device comprises an integrated circuit.
- 1 22. (previously presented) A method as in claim 24 wherein step (a) includes a transfer molding process.
- 1 23. (previously presented) A method as in claim 24 wherein step (a) includes a potting process.
- 1 24. (Currently amended) A method of making a semiconductor device 2 comprising:
- 3 (a) sealing the semiconductor device in a package by surrounding it with 4 thermosetting resin and thermally curing the resin at a first temperature;
- 5 (b) baking the thermosetting resin at a second temperature <u>not</u> higher than the 6 first temperature, wherein the second temperature is between about 220°C and about 260°C; and;

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7	(c) further baking the thermosetting resin at a third temperature higher than
8	the first temperature, wherein the third temperature is between about 220°C and about 260°C;
9	<u>and</u>
10	[[(c)]](d) inspecting the semiconductor device.
1	25. (previously presented) A method as in claim 24 wherein a conductive lead is
2	adhesively affixed to a main surface of the semiconductor device.
1	26. (previously presented) A method as in claim 25 wherein the conductive lead
2	is adhesively affixed to a peripheral portion of the main surface of the semiconductor device.
1	27. (previously presented) A method as in claim 26 wherein an electrode of the
2	semiconductor device is electrically connected to the conductive lead.

28-30 (canceled)